What is Claimed Is:

1. A method of manufacturing a magnetic film comprising steps of:

forming a magnetic layer on a substrate; defining a first area and a second area of the magnetic layer;

treating the first area of the magnetic layer with an ion bean to form a first area having a first direction; and

treating the second area of the magnetic layer with an ion beam in a magnetic field to form a second easy axis having a second direction.

- 2. The method of manufacturing a magnetic film of claim 1 wherein the magnetic laver comprises an rare earth material selected at least one of Pt, Pd, Au, and Tb.
- 3. The method of manufacturing a magnetic film of claim 1 wherein the angle difference between the direction of the first easy axis and that of the second easy axis is from 60° to 90° .
- 4. The method of manufacturing a magnetic film of claim 1 wherein the magnetic layer comprises a transition metal selected at least one of Co, Ni, and Fe.
- 5. The method of manufacturing a magnetic film of claim 1 wherein the beam comprises an inert gas selected at least one of He, Ne, Ar, Xe, and Kr.

6. A method of manufacturing a magnetic film comprising steps of: forming a magnetic layer on a substrate; and applying an ion beam into a selected area of the magnetic layer to form a first easy axis having a first direction.

7. The method of manufacturing a magnetic film of claim 6 further comprising steps of:

applying a magnetic field to the magnetic film and applying an ion beam into another selected area of the magnetic layer to form a second easy axis having a second direction.

- 8. The method of manufacturing a magnetic film of claim 6 wherein the magnetic layer comprises a transition metal selected at least one of Co, Ni, and Fe.
- 9. The method of manufacturing a magnetic film of claim 6 wherein the beam comprises an inert gas selected at least one of He, Ne, Ar, Xe, and Kr.
 - 10. A method manufacturing a magnetic film comprising steps of:

 forming a magnetic layer on a substrate; and

 treating the magnetic layer with an ion beam to form an easy axis having a direction.

- 11. The method of manufacturing a magnetic film of claim 10 wherein the magnetic layer comprises a transition metal selected at least one of Co, Ni, and Fe.
 - 12. A method manufacturing a magnetic film comprising steps of: forming a magnetic layer on a substrate;

applying a magnetic field to the magnetic film; treating the magnetic layer with an ion beam to form an easy axis having a direction.

- 13. The method of manufacturing a magnetic film of claim 12 wherein the magnetic layer comprises a transition metal selected at least one of Co, Ni, and Fe.
 - 14. A method manufacturing a magnetic film comprising steps of:
 forming a magnetic layer on a substrate;
 covering the magnetic layer with a first mask opening a first area;
 treating the first area with an ion beam to form an first easy axis;
 rotating the magnetic layer in some degree;
 covering the magnetic layer with a second mask opening a second area; and
 treating the second area with an ion beam to form an second easy axis.
 - 15. A method manufacturing a magnetic film comprising steps of: forming a magnetic layer on a substrate; covering the magnetic layer with a first mask opening a first area;

treating the first area with an ion beam in a magnetic field to form an first easy axis; rotating the magnetic layer in some degree;

covering the magnetic layer with a second mask opening a second area; and treating the second area with an ion beam in a magnetic field to form an second easy

axis.